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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chen et al.

Serial No. 10/712,460

§ Group Art Unit: 1746

Filed: 11/13/2003

§ Examiner: To be determined

For: Semiconductor Wafer
Manufacturing Methods
Employing Cleaning Delay Period

§ Customer No.: 000042717

§ Attorney Docket No.:
TSMC2002-1015/24061.42

TRANSMITTAL

Mail Stop Amendment
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed are the following for filing in the above-identified patent application:

1. Preliminary Amendment (3 pages);
2. Second Information Disclosure Statement (1 page);
3. PTO-1449 Form with copy of cited reference; and
4. a return postcard.

The Commissioner is hereby authorized to charge any fee deficiencies or credit any over payment to the Deposit Account of Haynes and Boone, LLP 08-1394. This form submitted in duplicate.

Respectfully submitted,

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Date: 10-7-04

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Date

10-7-04
Bonnie Boyle
Bonnie E. Boyle